Chapter

 $\mathbf{5}$

DEFECT AND CARRIER-CARRIER SCATTERING

GENERAL APPROACH TO SCATTERING DOMINATED TRANSPORT



IONIZED IMPURITY SCATTERING

Base scattering potential: Charge = Ze

$$U(r) = \frac{Ze^2}{4\pi\varepsilon} \quad \frac{1}{r}$$



Comparison of screened and unscreened Coulomb potentials of a unit positive charge as seen by an electron. The screening length is λ^{-1} .

Screened Coulombic potential:

$$U(r) = \frac{Ze^2}{4\pi\varepsilon} \frac{e^{-\lambda r}}{r}$$

Low free carrier density (n_0) :

$$\lambda^2 = \frac{n_0 e^2}{\varepsilon k_B T}$$



Typical measurements of electron mobility as a function of temperature in a uniformly doped GaAs with $N_D = 10^{17}$ cm⁻³. The mobility drops at low temperature due to ionized impurity scattering becoming very strong. In contrast, the curve (b) shows the mobility in a modulation doped structure where ionized impurity is essentially eliminated.

ALLOY SCATTERING LIMITED MOBILITY

In a semiconductor alloy there are random potential fluctuations from which electrons scatter.



A schematic of the actual atomic potential (solid line) and the average virtual crystal potential (dashed line) of an A-B alloy. The shaded area shows the difference between the real potential and the virtual crystal approximation.

3D systems:

$$\frac{1}{<<\tau>>} = \frac{3\pi^3}{8\hbar} V_0 U_{all}^2 x(1-x) - \frac{m^{*3/2}(k_B T)^{1/2}}{\sqrt{z}\pi^2\hbar^3} - \frac{1}{0.75}$$

AUGER PROCESSES AND IMPACT IONIZATION

Auger process:

Electron-hole recombination \rightarrow hot carrier



A schematic of the states of the electrons before and after an Auger scattering. The reverse of this process is the impact ionization process. This particular process is called CHCC (Conduction-heavy hole-conduction conduction).

Impact ionization: Reverse of Auger recombination → hot carrier → e-h pair